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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Jiang et al.

Art Unit:

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Serial No.:

09/966,605

Examiner:

Vinh, L.

Filing Date:

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Docket No.: TI-31462

Title:

IN-SITU PLASMA ASH/TREATMENT AFTER VIA ETCH OF LOW-K FILMS FOR POISON-FREE DUAL DAMASCENE

TRENCH PATTERNING

CERTIFICATION OF FACSIMILE TRANSMISSION

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